

Investigating 2D semiconductor contacts for Cooper-pair light-emitting diode applications

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Aalto University

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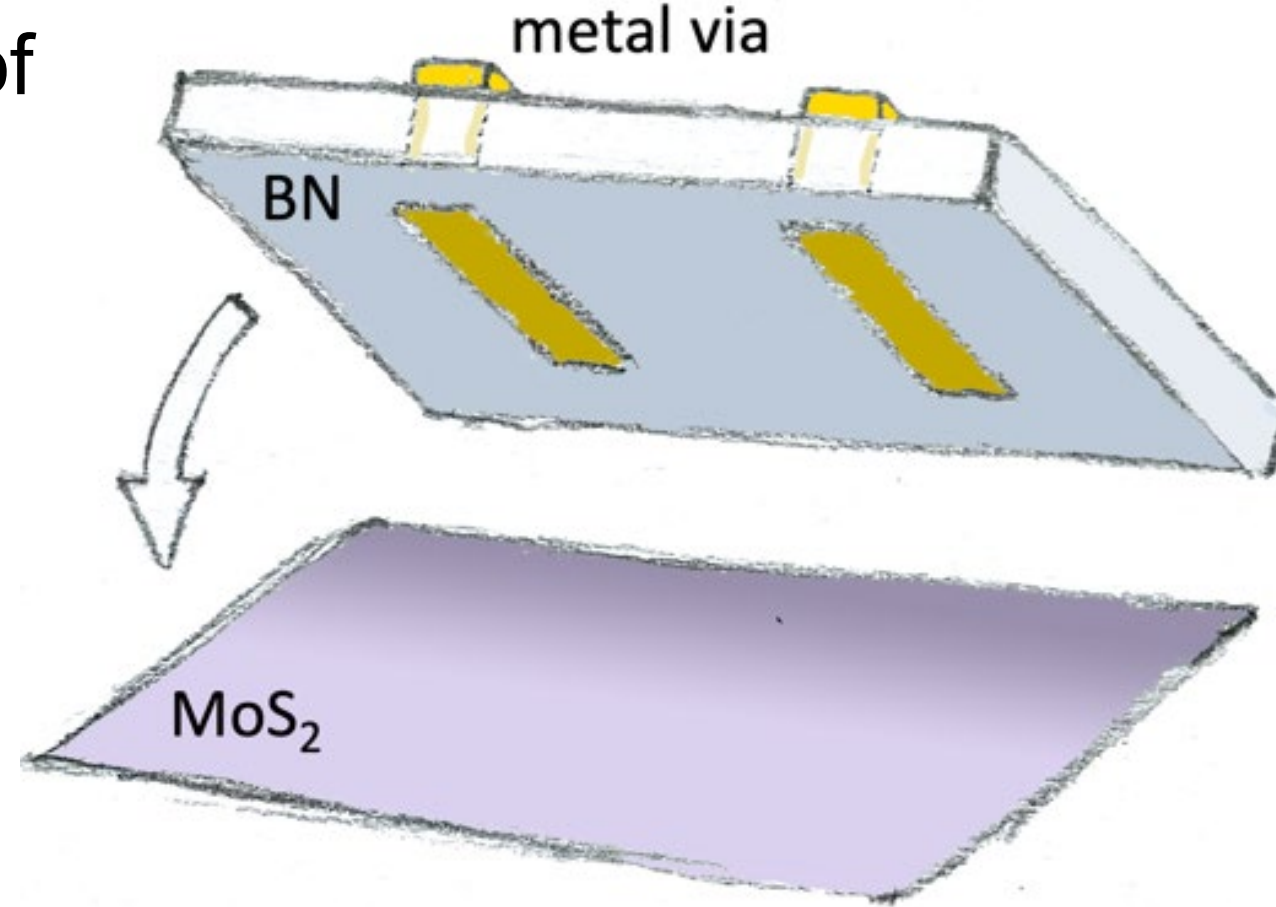


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Abstract

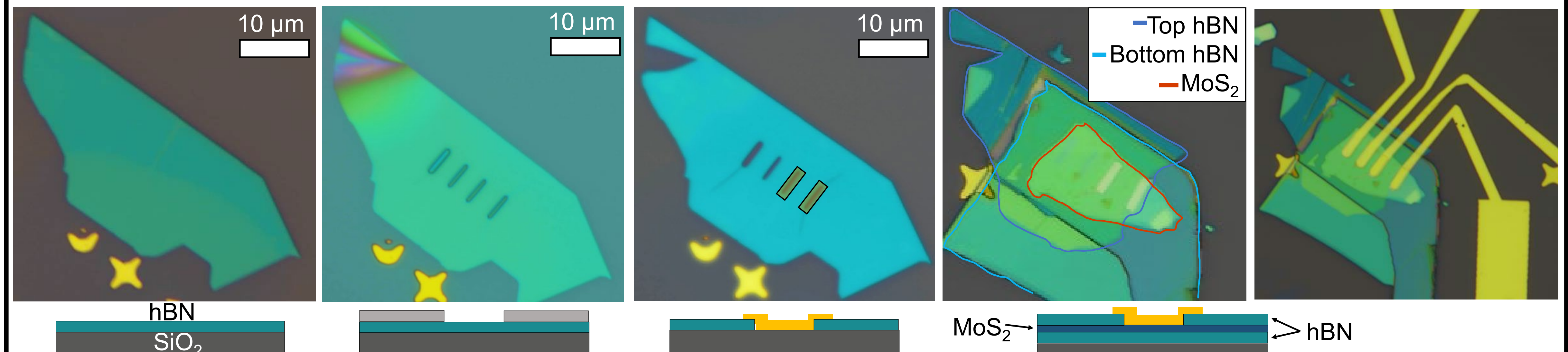
Future quantum technologies will require high-efficiency, on-demand sources of entangled photons. A possible route to building such light sources employs two-dimensional (2D) semiconductors interfaced with a source of Cooper pairs.

To investigate the possibility of such devices, we are testing methods to make high transparency transferred metal contacts to 2D semiconductors, following the pioneering work of Liu et al. [1]



VIA Fabrication

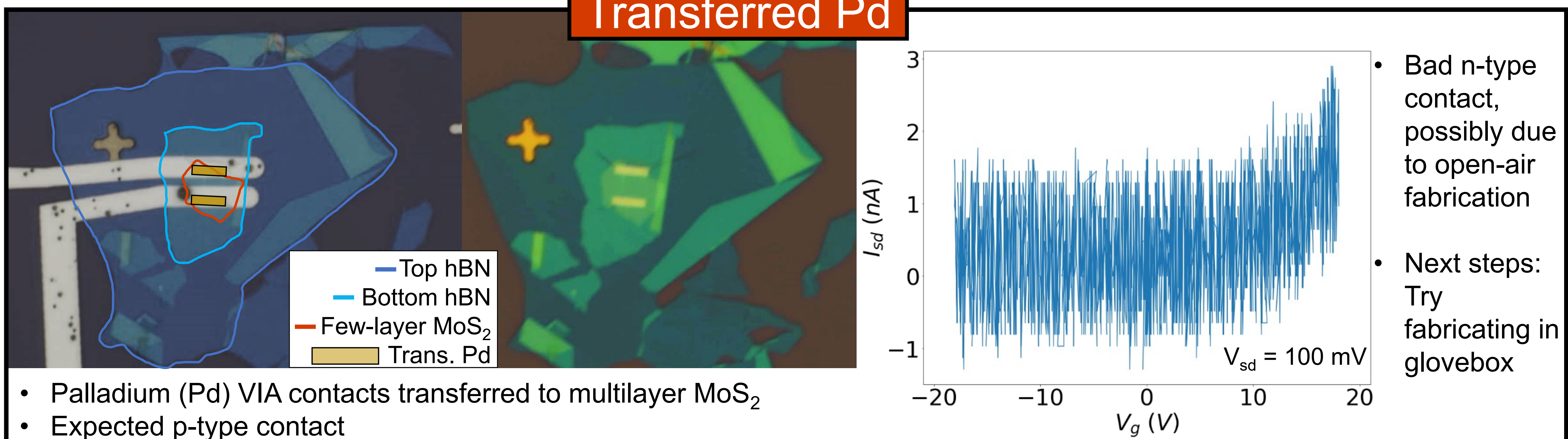
1. Exfoliate hBN, identify ~30 nm flake by color
2. EBL: Print etch pattern in PMMA
3. Etch hBN/evaporate metal†
4. Encapsulate MoS₂ with VIA-contact hBN
5. Evaporate onto VIA contacts



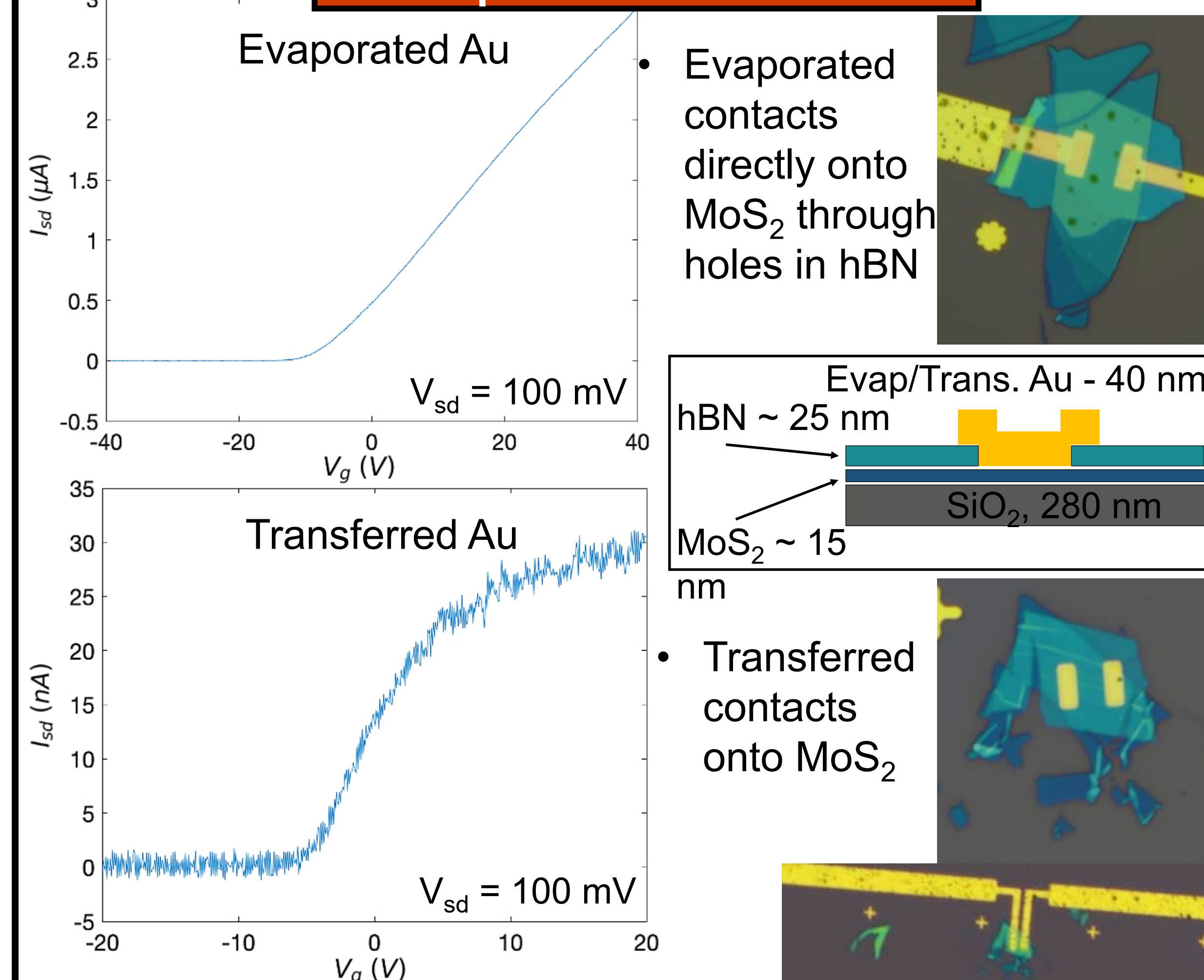
Background

- The “second quantum revolution,” a new era of technology with more secure communication networks, better quantum sensors, and universal quantum computers, relies on controllable quantum entanglement [2]
- Theoretical proposals: Entangled pairs of electrons in a superconductor can be converted into entangled pairs of photons by interfacing a superconductor layer with a semiconductor layer [3], [4]
- This approach needs high-quality n-type and p-type contacts to a 2D semiconductor that work at cryogenic temperatures; transferred metal VIA contacts have been shown to satisfy these requirements [1]

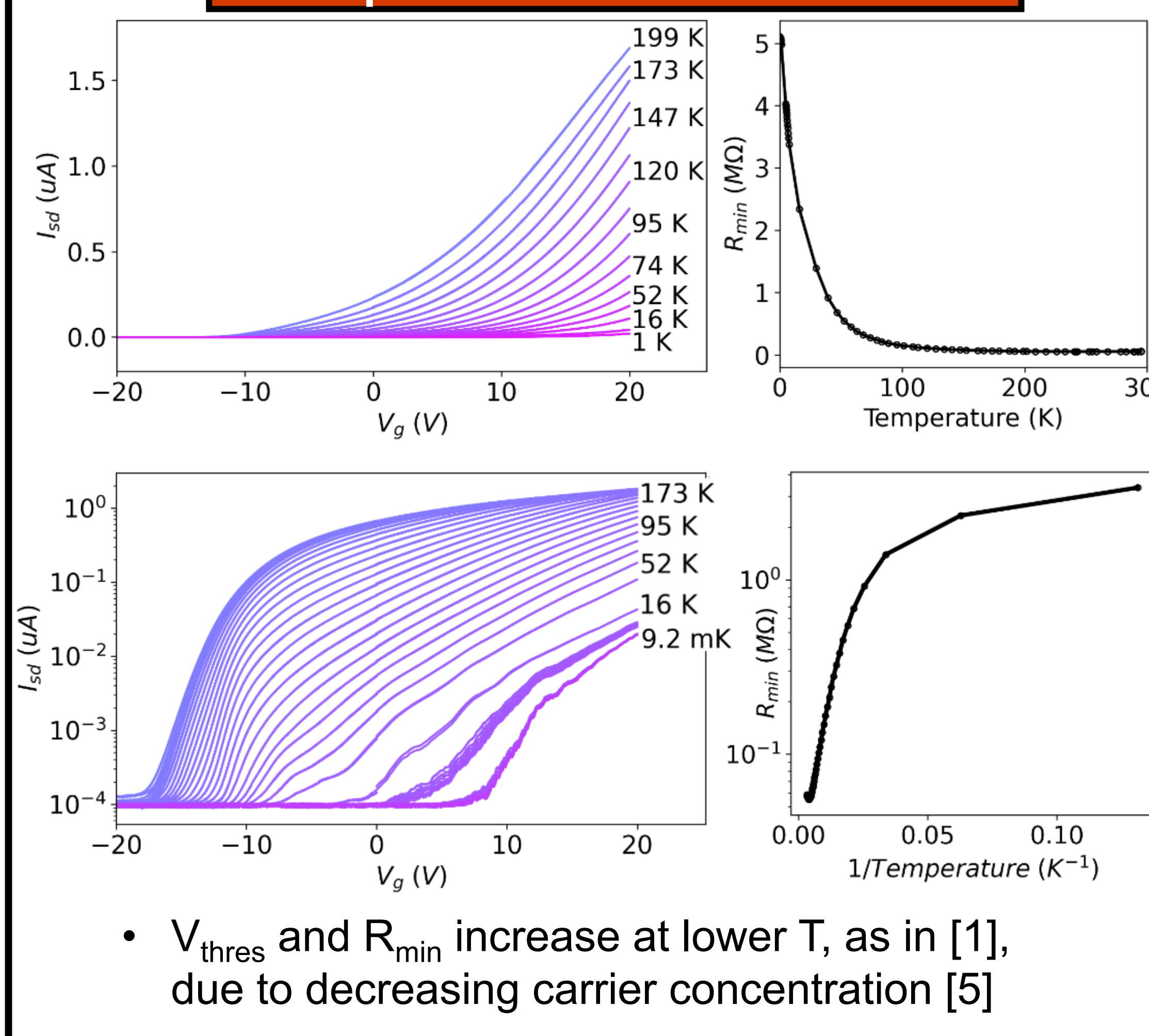
Transferred Pd



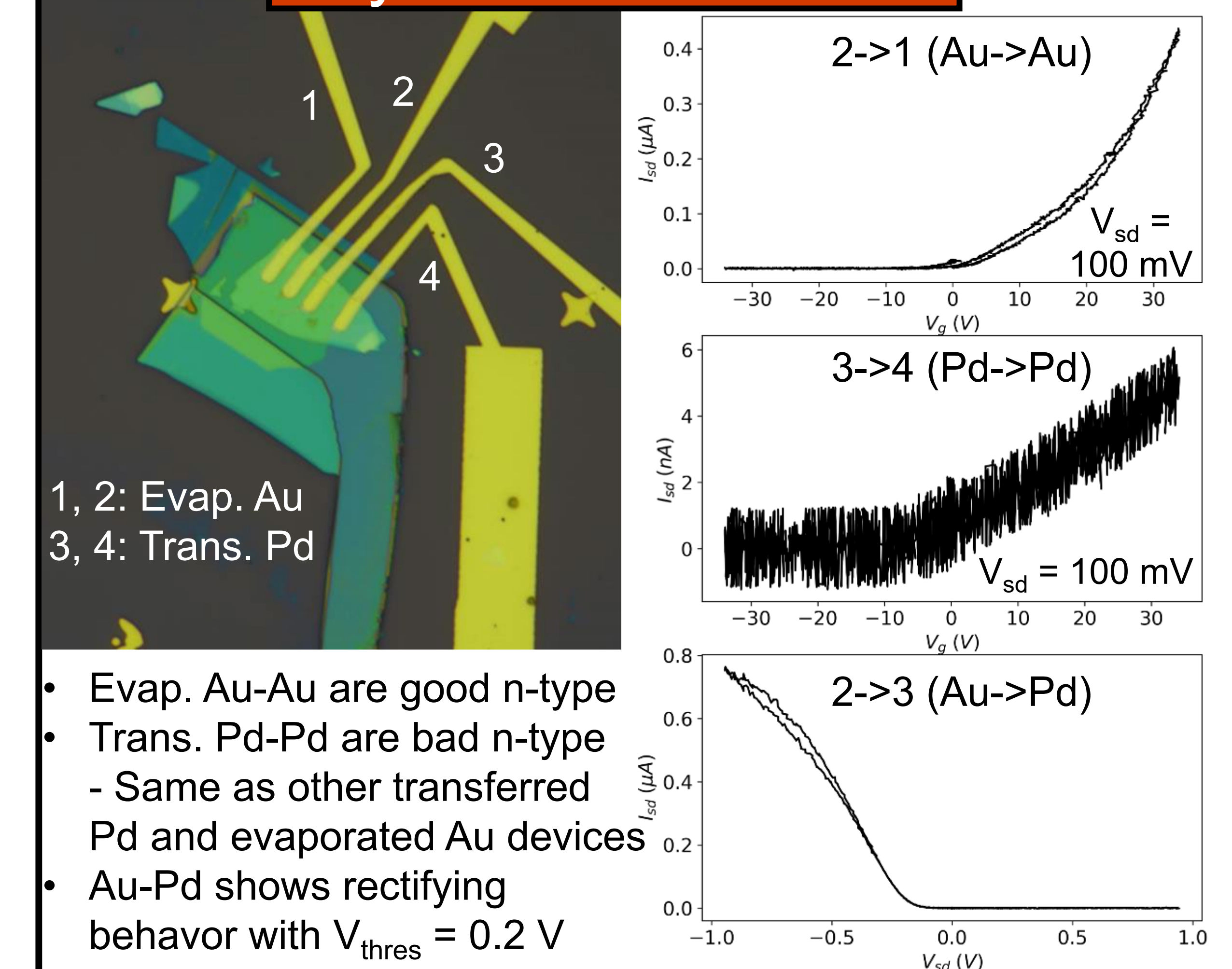
Evap. vs Trans. Au



Evaporated Au to 9 mK



Asymmetric Contacts



[1] Liu, Y., Guo, J., Zhu, E. et al. *Nature* **557**, 696–700 (2018). doi.org/10.1038/s41586-018-0129-8

[2] “Quantum Manifesto: A New Era of Technology,” (2016). [Online]. https://qt.eu/engage/resources/

[3] I. Suemune et al., *Japanese J. Appl. Physics*, **45**, 12, 9264–9271, (2006), doi: doi.org/10.1143/JJAP.45.9264

[4] A. Hayat, H. Y. Kee, K. S. Burch, and A. M. Steinberg, *Phys. Rev. B* **89**, 9, p. 094508, (2014), doi.org/10.1103/PhysRevB.89.094508.

[5] Liu, X., He, J., Liu, Q. et al. *J. Appl. Phys.* **118**, 124506 (2015), https://doi.org/10.1063/1.4931617

† The metal pads are made 0.5 μm larger than the etch holes to ensure they are transferred with the hBN. Etch parameters: CHF₃:O₂ 40:4 sccm with 60 W RF power and 60 mTorr gas pressure